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52. (Replacement) A method according to claims 33, 34, 36, 37, 42 or 43, wherein there are a plurality of said second substrates mounted to said first substrate.

REMARKS

Reconsideration is respectfully requested in view of any changes to the claims and the remarks herein. Please contact the undersigned to conduct a telephone interview in accordance with MPEP 713.01 to resolve any remaining requirements and/or issues prior to sending another Office Action. Relevant portions of MPEP 713.01 are included on the signature page of this amendment.

Claims 25-52 have been rejected under 35 USC 112, second paragraph. The following is an exemplary list of responses to the Examiner's queries in paragraph 3 of the office action. Applicants' do not intent to be limited by this list since the claims read more broadly. Referring to Fig. 2 in regards to claim 29, 68 is for example the "first substrate" and 54 is for example the "second substrate". In regards to claim 42, "The large substrate" is replaced with "the first substrate". In regards to claim 44, "a plurality of electrical connections" are represented by 72 in Fig. 2. In claims 43 and 44, "the second" has been changed to "the second substrate". In regard to claim 45, "a plurality of probe elements" are for example 46 in Fig. 2 and 120 in Fig. 10; "a space transforming substrate" has been changed to "a first substrate" having the exemplary meaning given above. A "second substrate" has the exemplary meaning given above. In the last line of claim 45, "at least one first substrate" is changed to "at least one second substrate" which, for example, is 60 in Fig. 2. "Means for effecting electrical interconnection" is, for example, 64 of Fig. 2. In claim 47, an example of a "tip structure" is a ball at the end of probe elements 120 in Fig. 10 as described in US Patent 5, 376,654 incorporated by reference in the specification on page 8. The word "are" has been added to claim 42 to positively claim "tip structure".

In regard to claim 52, "a plurality of second substrates" is explained in the remarks of the preliminary amendment which states "Support for the added claims is found throughout the specification, in particular in US Patent 5,371,654, col. 6, lines 39-57, which patent is incorporated by references as US Application Serial Number 07/963,364 on page 8. Also, Fig. 3 shows an example of an embodiment where substrate 54 is electrically coupled to substrate 68 for example by interposer 76." A copy of US 5,371,654 is attached herewith.

Claims 29-32, 35, 38-41, 44-46, and 50-51 have been rejected under 35 USC 102(b) as anticipated by Bove et al. (US 4,038,599). Applicants respectfully disagree and respectfully request withdrawal of this rejection. Claims 33, 34, 36, 37, 42, 43, 47-49 and 52 have not been rejected over Bove et al. and have been written in independent form and should thus be patentable over Bove et al.

Original claim 52, a multiple dependent claim, has been rewritten as the three independent claims 52, 53 and 54. The Examiner states "[i]t appears that the probe elements [19] are flexible". Applicants respectfully disagree. Bove et al. provides no description of "probes 19" other than to call "19" a probe. At Col. 5, lines 10-21, Bove et al. states "[t]he assembly of probes may be similar to, or patterned after the probe assembly disclosed ... in ... Bove US Patent No. 3, 806, 801.", which is entitled "Probe Contactor Having Buckling Beam Probes". The American Heritage Dictionary Second College Edition, defines buckle to mean "to cause to bend, warp or crumple". US Patent 5,367,254 shows a picture of a buckled beam. See the copy of this patent enclosed herewith which shows a buckled beam 5 in the figure thereof. In contradistinction, independent claim 29 has been amended to recite "the flexible contact elements have an original shape; the flexible contact elements deflect away from the original shape when said flexible contacts contact the electronic components; the flexible contact elements substantially return to the original shape when the flexible contact elements are withdrawn from contacting the electronic component.", for which there is no teaching or suggestion in Bove et al. '599. Bove et al. '500 teaches away

from amended claim 29 since it teaches "buckling beams" which bend, warp or crumple." A crumpled beam cannot "substantially return to its original shape". Figure 8 of US Patent 3,806,801 shows graphically the relationship of force and deflection of an axially loaded probe as taught in Bove et al. '599. The buckling of this probe is described at Col. 1, lines 54-64 and Col. 6, lines 10-35 of US 3,806,801, in particular, Col. 6, lines 27-30 teaches, "The wire 16 of the probe 15 is designed in accordance with formula ... where F is an axial load on the end of the wire 16 which will cause buckling of the wire 16."

Claim 49 has been amended recite "free standing electrical conductors" and to recite "the plurality of the first substrates are mounted on to the second substrate" for which there is no teaching or suggestion in Luttmmer. In view thereof, withdrawal of the rejection of claim 49 under 35 USC 103(a) as obvious in view of Luttmmer is respectfully requested.

Attached herewith are copies of the Forms PTO 1449 submitted by the Applicants and PTO 892 provided by the Examiner in US Application Serial No. 08/055,485 filed 04-03-1993, and the progeny thereof which are:

1. IBM Docket No.: YOR9-1993-0028-US1
Application Serial No.: 08/055,485
Filing Date: April 30, 1993
Granted: US Patent No. 5,635,846 on June 3, 1997
2. IBM Docket No.: YOR9-1993-0028-US2
Application Serial No.: 08/754,869
Filing Date: November 22, 1996
Granted: US Patent No. 5,821,763 on October 13, 1998
3. IBM Docket No.: YOR9-1993-0028-US3

Serial No.: 09/382,834

- 19 -

YO993-028BX

Application Serial No.: 09/088,394

Filing Date: June 1, 1998

4. IBM Docket No.: YOR9-1993-0028-US4

Application Serial No.: 09/382,834

Filing Date: August 25, 1999

5. IBM Docket No.: YOR9-1993-0028-US5

Application Serial No.: 08/872,519

Filing Date: June 11, 1997

Enclosed is a PTO 1449 and PTO 892 listing all these reference.

In view of the changes to the claims and the remarks herein, the Examiner is respectfully requested to reconsider the above-identified application. If the Examiner wishes to discuss the application further, or if additional information would be required, the undersigned will cooperate fully to assist in the prosecution of this application.

Please charge any fee necessary to enter this paper and any previous paper to deposit account 09-0468.

If the above-identified Examiner's Action is a final Action, and if the above-identified application will be abandoned without further action by applicants, applicants file a Notice of Appeal to the Board of Appeals and Interferences appealing the final rejection of the claims in the above-identified Examiner's Action. Please charge deposit account 09-0468 any fee necessary to enter such Notice of Appeal.

Serial No.: 09/382,834

- 20 -

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In the event that this amendment does not result in allowance of all such claims, the undersigned attorney respectfully requests a telephone interview at the Examiner's earliest convenience.

MPEP 713.01 states in part as follows:

Where the response to a first complete action includes a request for an interview or a telephone consultation to be initiated by the examiner, ... the examiner, as soon as he or she has considered the effect of the

response, should grant such request if it appears that the interview or consultation would result in expediting the case to a final action.

Respectfully submitted,

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The electrical interconnection means 49 is formed to occupy the space between the chips as shown in FIGS. 1-4. The structure of FIG. 1 is compressed from the top and bottom of the structure to compress the electrical interconnection means 46 between the adjacent assemblies pressing electrical contact locations 30 on substrate 8 in contact with electrical contact locations 50 on electrical interconnection means 49 and pressing electrical contact locations 54 on electrical interconnection means 49 in contact with electrical contact locations 18 on the surface of the thin film wiring layer 12. Thus, a signal from any one chip will travel in the thin film wiring layer and vertically through the electrical interconnection wiring means 49 to any thin film wiring plane in the stack of substrates 8 and thus along the shortest path to any chip in the entire structure 2. If a single plane contained 25 chips, for example, as shown in FIG. 3, each being 1 centimeter square, then the electrical interconnection means 46 would occupy the 1 centimeter space between each chip. With this design point the vias in the substrates 8 and the connections in the electrical interconnection means 49 could be made on a 36 mil square grid with 20 mil wide pads 18 on the substrate 8. There would be approximately 6,694 vertical signal connections possible on one plane. The grid could be reduced by a factor of approximately 2 if required and 26,000 vertical connections could be made.

The overall high performance package can consist of as many insulating plates populated by chips as required. The heat would be conducted to the edges of the high thermal conductivity substrates 8 where it would be carried away by air or water cooled or the like heat sinks as appropriate and commonly known in the art.

The substrates are preferably made of a high thermally conductive insulating material made of commercial diamond (manufactured for example by NORTON Inc. and Diamond Inc.) which can be laser drilled to form vias and metallized for through hole connections using standard processing such as the process used on diamond heat spreaders for diode lasers. The very high thermal conductivity of diamond (1500 W/m² K.) makes it the most desirable material in this structure and would allow the cooling of more than 100 watts per plane. Other materials are useful. A lower cost alternative would be AlN ceramic with co-sintered solid vias, which are commercially available or silicon wafers which can contain laser drilled holes or chemically etched through vias. The thin film wiring layer 12 and 24 preferably contains copper wiring in a polyimide dielectric and can be fabricated by standard sequential thin film processes directly onto substrate 8 as described in R. Tummala and E. Rymaszewski, Microelectric Packaging Handbook, Van Nostrand, Reinhold, N.Y., 1989 Chapter 9, the teaching of which is incorporated herein by reference. The thin film wiring structure can be fabricated separately by the serial/parallel thin film wiring process and joined to the substrates 8 as described in U.S. patent application Ser. No. 07/695,368, filed May 3, 1991, the teaching of which is incorporated herein by reference. In the serial/parallel processes the thin film wiring structures are fabricated on separate carriers then transferred and laminated to the insulated plates preferably by thermal compression bonding. The electrical interconnection means 49 preferably contains gold wires held at a slight angle in an elastomeric matrix. Other embodiments of large area array connectors can also work. The electrical interconnection means 49

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using an elastomeric matrix has desirable properties such as lower resistance, low contact force, wipe, and low inductance which makes it particularly desirable in this application. The electrical interconnection means 49 can be fabricated to be approximately 1 millimeter thick with 10 percent compliance.

The substrates 8 are made with conducting vias. Top and bottom surface pads are applied by standard techniques such as evaporation of metals through a metal mask as described in Tiemmla et al., chapter 9 above. The electronic devices 36 and 38 are joined to each thin film wiring layer after the electronic devices are tested and burned in. The electrical interconnection means 49 are fabricated separately and tested. Finally, the stack of assemblies with electronic devices mounted onto the substrates with the electrical interconnection means 49 disposed thereon are aligned and a compressive force is applied to make the interconnections. The force is preferably from 10 to 50 grams per contact or from 70 to 300 kilograms for the entire package. The connection is separable.

FIGS. 5-21 show the method for fabricating electrical interconnection means 49 of FIG. 1 and show various embodiments and fabrication techniques of this electrical interconnection means.

FIG. 5 shows electrical interconnection means 80 which corresponds to electrical interconnection means 49 of FIG. 1. The electrical interconnection means 80 is formed from an elastomeric material 82 having a plurality of electrical conductors 84 extending from side 86 to side 88 thereof. Each conductor 84 preferably has a generally spherical end 90 at side 86 and a flattened spherical shape 92 at side 88. The conductors 84 are preferably gold, gold alloy or copper alloy. The size, shape and the spacing of wires 84 along with the material properties of the elastomeric material 82 can be modified to optimize the connector for a specific application.

FIG. 6 shows substrate 94 and 96 pressed towards each other as indicated by arrows 98 and 100 with interposer 80 therebetween. The elastomer 82 acts as a spring to push the enlarged end contact surfaces 90 and 92 against mating contacts 104 and 106 on substrates 94 and 96 respectively. Surface 102 of substrate 94 has contact locations 104 which are typically metallized pad. Substrate 96 has contact locations 106 which are also typically metallized pads. When substrate 94 is pressed towards substrate 96 the ends 90 and 92 move laterally with respect to the contact surface because conductors 84 are at a nonorthogonal angle with respect thereto. This lateral movement results in a wiping action which breaks a surface oxide which is on the surface of the contact locations 104 and 106 and which is on the surface of the enlarged ends 90 and 92. The wiping action makes a good electrical contact between the enlarged surface 90 and 92 and the contact locations 104 and 106, respectively.

The advantages and unique features of the electrical interconnection means 80 are that it provides uniform spacing of the electrical conductors 84 and the elastomeric material on, for example, a 0.008 inch minimum pitch using a single wire per contact. The enlarged ball shaped contacts 90 protrude from top side 86 of interconnection means 80 and the enlarged, flattened contacts 92 are generally flush with the bottom surface 88 of interconnection means 80. Textured or raised contact surface can be formed on the bottom side of the contact 92 to enhance the contact interface to an electri-

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7

cal contact location on substrate 96. The wires 84 in the elastomer material 82 can be grouped into small clusters to provide redundant connections for each contact location 104 or 106. If clustered wires are used, wires 95 in interconnect structure 80 of FIG. 6 would be eliminated.

FIG. 7 shows a cross section of another embodiment 110 corresponding to the electrical interconnection means 49 of FIG. 1. Structure 110 has electrical conductors 112 which are clustered into groups 114. Between each group there are grooves 116. The elastomer material 118 is preferably a silicone elastomer and there are ball shaped contacts 120 on side 122 and flat contact 124 on side 126 having a raised surface 128. The top and bottom wire shapes can be varied for optimization. The alignment grooves 116 of structure 110 can be formed using a laser, electron beam or other sensing techniques as described in U.S. Pat. No. 4,998,885, to Beaman, the teaching of which is incorporated herein by reference.

Alignment features 116 can be molded into the elastomer material to allow accurate alignment of the conductors 112 in the structure 110 with contact locations 104 and 106 on surfaces 102 and 105, respectively, as shown in FIG. 6. An alignment mechanism is preferred to enhance accurate positioning of the interposer wires with the contacts on the adjacent substrates. The molded alignment features can also be used to control the shrinkage and distortion of the contact grid in the elastomer material. Mechanically or thermally induced stress in the elastomer material can cause the interposer or distort causing alignment problems with the mating contacts.

The electrical interconnection means shown in FIGS. 5, 7 and 8 and electrical interconnection means 49 of FIG. 1 will also be referred to herein as an ELASTICON interposer. The ELASTICON interposer is designed to provide signal and power connections from the bottom surface of a substrate to another substrate. The ELASTICON interposer can be fabricated to have a full array of conductors or a clustered array of conductors. The interposer connector that uses a full array of conductors (or wires) would typically not require alignment of the connector to the contact locations on the substrate between which is disposed. By using clusters of wires, overall fewer wires are used to fabricate the interposer. This is useful for reducing the cost of the connector and the pressure required to ensure full engagement of the contacts. Interposer contacts that use a clustered array of wires preferably have a means for aligning the wire clusters with the remaining said contacts. An interposer having a cluster set of wires minimizes the number of wires required during the interposer fabrication and enhances the compliance of the connector assembly. The molded or scribed grooves or other features in the elastomer material can be used to allow the interposer connector to self align with similar features on the substrates between which it is disposed as shown in FIG. 8. FIG. 8 shows interposer 119 disposed on substrate 121. Interposer 119 has grooves 123 which mate with projections 125 on substrate 121 which aligns substrate pads 127 to interposer contact locations 129. These alignment features can be designed using a variety of simple geometric shapes such as circular post, rectangular ridges, or a raised grid pattern. FIG. 10 shows a perspective view of an ELASTICON interposer useful as the electrical interconnection means 49 of FIG. 1. The ELASTICON interposer 134 of FIG. 10 has a plurality of alignment grooves 136

8

and regions 138 containing clustered contacts wherein each region is surrounded by grooves 140.

FIG. 9 shows an alignment frame 142 which is adapted for engagement with the grooves on the interposer 134 of FIG. 10 to align substrate contact locations to interposer contact locations. For example, bar 144 in alignment frame 142 engages groove 146 of structure 134 of FIG. 10 and bar 148 of frame 142 engages groove 150 of structure 134 of FIG. 10. The frame is disposed on a substrate having contact locations to which interposer contact locations are to be aligned.

An overall alignment scheme is preferred to fabricate the structure of FIG. 1. Each of the disconnectable elements of the module preferably have a means of alignment to the other elements in the module. A separate alignment frame could be attached to each substrate similar to the one used for the interposer.

FIGS. 11-19 show a fabrication method for the ELASTICON interposers described herein.

The fabrication process starts with a sacrificial substrate 160, which is preferably copper, copper/Invar/copper or copper/molybdenum copper. Materials other than copper can be used such as aluminum, hard plastic or steel. The substrate 160 can be fabricated to have protuberances 162 which provide the grooves 116 in the ELASTICON interposers of FIG. 7. The protuberances 162 can be formed using various fabrication techniques including machining of the surface 164 or stamping of the surface 164. After the substrate has been formed with the protuberances, the top surface 164 is sputtered or plated with soft gold or Ni/Au to provide a suitable surface for thermosonic ball bonding. Other bonding techniques can be used such as thermal compression bonding, ultrasonic bonding, laser bonding and the like. A commonly used automatic wire bonder is modified to ball bond gold, gold alloy, copper, copper alloy, aluminum, nickel or palladium wires 166 to the substrate surface 164 as shown in FIG. 11. The wire preferably has a diameter of 0.001 to 0.005 inches. If a metal other than Au is used, a thin passivation metal such as Au, Cr, Co, Ni or Pd can be coated over the wire by means of electroplating, or electroless plating, sputtering, e-beam evaporation or any other coating techniques known in the industry. Structure 168 of FIG. 11 is the ball bonding head which has a wire 170 being fed from a reservoir of wire as in a conventional wire bonding apparatus. FIG. 11 shows the ball bond head 168 in contact at location 169 with surface 164 of substrate 160.

FIG. 12 shows the ball bonding head 168 withdrawn in the direction indicated by arrow 171 from the surface 164 and the wire 170 drawn out to leave disposed on the surface 164 wire 166. In the preferred embodiment, the bond head 168 is stationary and the substrate 160 is advanced as indicated by arrow 161. The bond wire is positioned at an angle preferably between 5° to 60° from vertical and then mechanically severed by knife edge 172 as shown in FIG. 13. The knife edge 172 is actuated, the wire 170 is clamped and the bond head 168 is raised. When the wire 170 is severed there is left on the surface 164 of substrate 160 a flying lead 166 which is bonded to surface 164 at one end and the other end projects outwardly away from the surface. A ball can be formed on the end of the wire 166 which is not bonded to surface 164 using a laser or electrical discharge to melt the end of the wire. Techniques for this are commonly known in the art. A split beam laser delivery systems, described hereinbelow, is used to localize the laser energy to a

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6

using an elastomeric matrix has desirable properties such as lower resistance, low contact force, wipe, and low inductance which makes it particularly desirable in this application. The electrical interconnection means 49 can be fabricated to be approximately 1 millimeter thick with 10 percent compliance.

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7

cal contact location on substrate 96. The wires 84 in the elastomer material 82 can be grouped into small clusters to provide redundant connections for each contact location 104 or 106. If clustered wires are used, wires 85 in interconnect structure 80 of FIG. 6 would be eliminated.

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Alignment features 116 can be molded into the elastomer material to allow accurate alignment of the conductors 112 in the structure 110 with contact locations 104 and 106 on surfaces 102 and 105, respectively, as shown in FIG. 6. An alignment mechanism is preferred to enhance accurate positioning of the interposer wires with the contacts on the adjacent substrates. The molded alignment features can also be used to control the shrinkage and distortion of the contact grid in the elastomer material. Mechanically or thermally induced stress in the elastomer material can cause the interposer or distort causing alignment problems with the mating contacts.

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An overall alignment scheme is preferred to fabricate the structure of FIG. 1. Each of the disconnectable elements of the module preferably have a means of alignment to the other elements in the module. A separate alignment frame could be attached to each substrate similar to the one used for the interposer.

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FIG. 12 shows the ball bonding head 168 withdrawn in the direction indicated by arrow 171 from the surface 164 and the wire 170 drawn out to leave disposed on the surface 164 wire 166. In the preferred embodiment, the bond head 168 is stationary and the substrate 160 is advanced as indicated by arrow 161. The bond wire is positioned at an angle preferably between 5° to 60° from vertical and then mechanically severed by knife edge 172 as shown in FIG. 13. The knife edge 172 is actuated, the wire 170 is clamped and the bond head 168 is raised. When the wire 170 is severed there is left on the surface 164 of substrate 160 a flying lead 166 which is bonded to surface 164 at one end and the other end projects outwardly away from the surface. A ball can be formed on the end of the wire 166 which is not bonded to surface 164 using a laser or electrical discharge to melt the end of the wire. Techniques for this are commonly known in the art. A split beam laser delivery systems, described hereinbelow, is used to localize the laser energy to a

5,371,654

10

single wire for forming the ball. This minimizes the laser energy absorbed by adjacent wires that could cause the wires to deform. A ball is not required on the end of the wire. This modified wire bonding process is repeated to form a dense array of angled wires on the substrate.

FIG. 14 shows the wire 170 severed to leave wire 166 disposed on surface 164 of substrate 160. The wire bond head 168 is retracted upwardly as indicated by arrow 174. The wire bond head 168 has a mechanism to grip and release wire 170 so that wire 170 can be tensioned against the shear blade to sever the wire.

FIG. 15 shows that the wire is severed, the bond head is raised to a "home" position. An electronic flame off unit (part of Hughes Wire Bonder, Model III-2640) electrode is positioned below the bond head and an electrical discharge from the electrode is used to melt the wire in the capillary tip to form a ball.

After the wire bonding process is completed, the substrate 160 is placed in a casting mold 190 as shown in FIG. 16. A controlled volume of liquid elastomer 192 is disposed into the casting mold and allowed to settle out (flow between the wires until the surface is level) before curing as shown in FIG. 17. Once the elastomer has cured, the substrate is extracted from the mold as shown in FIG. 18 and indicated by arrow 194. The cured elastomer is represented by reference numeral 196. Opening 161 in mold 190 is a tooling feature for extracting the substrate from the mold. The structure 198 is removed from the mold 190 and is placed in a sulfuric and nitric acid bath 200, as shown in FIG. 19 to dissolve the copper substrate 160. Ultrasonic agitation of the sulfuric and nitric acid helps to facilitate the etching of the copper substrate and causes the gold plating on the surface of the copper substrate to flake off from the surface 202 of the elastomer material 196 leaving the surface of the ball bonds 204 exposed.

Alternatively, the substrate can be made of peel-apart-copper, where a thin layer of copper is attached to a solid substrate with a marginal adhesion strength. After the fabrication is completed, the connector can be peeled off from the sacrificial substrate before the remaining thin copper is flash etched away.

A high compliance, high thermal stability siloxane elastomer material is preferable for this application. The high temperature siloxane material is cast or injected and cured similar to other elastomeric materials. To minimize the shrinkage, the elastomer is preferably cured at lower temperature ($T \leq 60^\circ$) followed by complete cure at higher temperature ($T \geq 80^\circ$). To further control the shrinkage, the connector is cast into a plastic frame, which was predrilled with holes around its periphery. When the elastomer is poured into this frame a physical locking of the elastomer to the frame takes place which both holds the elastomer/connector to the frame and minimizes the shrinkage. To improve the compliance and reduce the dielectric constant of the elastomer material, a foam agent can be blended into the commercial elastomeric material at a ratio ranging from 10 to 60%. Also, foam can be employed as a distinct layer.

Among the many commercially available elastomers, such as ECCOSIL and SYLGARD, the use of polydimethylsiloxane based rubbers best satisfy both the material and processing requirements. However, the thermal stability of such elastomers is limited at temperatures below 200° C. and significant outgassing is observed above 100° C. We have found that the thermal stability can be significantly enhanced by the incorporation of 25

wt % or more diphenylsiloxane (FIG. 1). Further, enhancement in the thermal stability has been demonstrated by increasing the molecular weight of the resins (oligomers) or minimizing the crosslink junction. The outgassing of the elastomers can be minimized at temperatures below 300° C. by first using a thermally transient catalyst in the resin synthesis and secondly subjecting the resin to a thin film distillation to remove low molecular weight side-products. For our experiments, we have found that 25 wt % diphenylsiloxane is optimal, balancing the desired thermal stability with the increased viscosity associated with diphenylsiloxane incorporation. The optimum number average molecular weight of the resin for maximum thermal stability was found to be between 18,000 and 35,000 g/mol. Higher molecular weights were difficult to cure and too viscous, once filled, to process. Network formation was achieved by a standard hydrosilylation polymerization using a hindered platinum catalyst in a reactive silicon oil carrier.

In FIG. 11 when bond head 168 bonds the wire 170 to the surface 164 of substrate 160 there is formed a flattened spherical end shown as 204 in FIG. 19. The protruberances 162 on substrate 160 as shown in FIG. 11 result in grooves in the elastomer such as grooves 116 shown in FIG. 7. These grooves form alignment features. The design and tolerances used to form the copper substrate 160 are preferably carefully matched with the design and tolerances used to fabricate the alignment features on the substrates 94 and 96 shown in FIG. 6. Alternatively, on a substantially flat substrate, an alignment frame, such as shown in FIG. 9, can be disposed on the surface of a substrate, such as 94 and 96, of FIG. 6 and the elastomer interposer with grooves can be disposed onto this alignment frame so that the alignment grooves of the interposer engage the frame pattern as described herein above with respect to FIGS. 9 and 10.

Referring to FIG. 20, multiple substrates 210 each having a group of wires 212 disposed thereon can be placed into a common mold 214 into which the liquid elastomer 216 as described herein above is disposed and cured. The cured elastomer links the substrates together into a single interposer 218 as shown in FIG. 21. Grooves 211 are for compliance or alignment requirements. Alternatively, several smaller connectors can be fabricated on the same substrate as a single unit and then separated after the elastomer is cured and the substrate is etched away.

Also, the surface of the copper sacrificial substrate can be textured or embossed prior to gold plating and wire bonding to provide a textured or raised contact surface on the bottom of the ball bonds. The completed interposer 218 of FIG. 21 can be further modified by using a laser to scribe channels in the elastomeric material between the bond wires at an angle matching the angle of the bond wires, as shown in FIG. 7. The crisscrossing channels create independent elastomeric columns (shown in FIG. 10 as 138) surrounding the gold wires. This would allow individual wires or groups of wires to compress independently and allow the interposer to compensate for slight variations in the remaining surfaces while reducing the total pressure required to compress the entire interposer. Patterned connectors can easily be fabricated by programming the wire bonder to a specific pattern and molding the elastomer to provide holes or open areas in the connector that correspond with other electronic or mechanical components surrounding the connector.

5,371,654

11

To improve compliance and reduce wire deformation, grooves are preferably molded into the elastomer on both sides of the connector surfaces in both the X and Y directions or in a circular geometry. The width and depth of the groove are preferably wider than 5 mills and deeper than 10 mills, respectively, in an interposer 100 mills thick. The grooves are preferably molded in a direction parallel to the angled wire.

Grooves have been fabricated with laser, electron beam, metal mask and slicing with a blade. Other techniques such as stamping, injection molding and other known techniques to create the desired geometry would also work well.

The contact balls at the end of the wires are formed using a split beam laser configuration. The end of each wire will melt and form the ball only at the point where the two beams intersect. The design is illustrated in FIG. 22 which shows light source 300, preferably an argon-ion laser which is the source of light beam 302 which is reflected as light beam 304 by mirror 306. Light beam 304 is directed through light beam expander 308 to form expanded light beam 310. Expanded light beam 310 is directed to beam splitter 312 which splits beam 310 into beams 314 and 316. Beam 316b is reflected off mirror 322 as light beam 324. Beam 314 is reflected off mirror 318 as light beam 320. Beam 320 is passed through focusing lens 328 to form focused beams 330 which focused onto spot 332 on the workpiece which is the end of a wire. Beam 324 is passed through focusing lens 334 to form focused beam 336 which is focused onto spot 332 on the workpiece. The workpiece is disposed on x-y table 338. The beam is expanded before focusing to get the desired size of spot 332.

FIG. 23 shows an enlarged view of the region of FIG. 7 enclosed in the dashed circle 230. Element 124 is a flattened ball shape member at the end of conductor 112. The flattened ball shaped member 124 was formed when conductor 112 was wire bonded to the sacrificial copper layer as described with reference to FIG. 11. The sacrificial copper layer can be fabricated with an array of pits in the surface in the regions where the wires 112 are bonded. These pits can have, for example, a hemispherical shape, rectangular shape, pyramidal shape or any other shape. If such an array of pits are used and the wire is bonded in the region of the pit, a protuberance such as 128 of FIG. 22 is formed at the surface 232 of flattened ball. This protuberance provides a projecting region to the contact formed by flattened ball 124 which can wipe on the surface of the contact location to which the flattened ball is to be electrically connected.

While the present invention has been described with respect to preferred embodiments, numerous modifications, changes and improvements will occur to those skilled in the art without the departing from the spirit and scope of the invention.

What is claimed is:

1. A three dimensional electronic package structure comprising:
 - a plurality of assemblies;
 - each of said plurality of assemblies comprises a substrate having a first and second opposing surface and a plurality of electronic devices disposed on at least one of said first and said second surfaces;
 - each of said plurality of assemblies is disposed adjacent another of said plurality of assemblies so that one of said first and said second opposing surfaces of one of said adjacent assemblies is adjacent one of

12

said first and said second opposing surfaces of the other of said adjacent assemblies;

an electrical interconnection means is disposed between said adjacent assemblies;

said electrical interconnection means comprises a dielectric material having first and second opposing surfaces and a plurality of electrical conductors extending from said first to said second opposing surface of said electrical interconnection means;

said electrical interconnection means provides electrical interconnection between said adjacent assemblies.

2. The structure of claim 1, wherein a dielectric layer of said electrical interconnection means is formed from an elastomeric material.

3. The structure of claim 2, wherein said elastomeric material has regions containing foam and solid materials.

4. The structure of claim 3, wherein said regions are a blend of said foam and said solid material.

5. The structure of claim 1, further including a means for pressing said plurality of assemblies together so that said electrical interconnection means is compressed between said adjacent assemblies.

6. The structure of claim 1, further including a heat sink in thermal contact with said substrates of each of said plurality of assemblies.

7. The structure of claim 1, further including a heat dissipation means in thermal contact with said structure.

8. The structure of claim 1, wherein said substrate is selected from the group consisting of a ceramic substrate, a glass ceramic substrate, a diamond substrate, a polymeric substrate, a glass substrate and a metal substrate and a silicon substrate.

9. The structure of claim 1, wherein said substrate is thermally conductive.

10. The structure of claim 1, wherein said electrical interconnection means has a plurality of electrical contact locations on said first and said second opposing surfaces of said electrical interconnection means and wherein said conductors are in electrical communication with said plurality of electrical contact locations.

11. The structure of claim 10, wherein said plurality of electrical contact locations are in electrical communication with a plurality of electrical contact locations on said adjacent assemblies.

12. The structure of claim 1, wherein each of said plurality of electrical conductors has an enlarged end at said first and said second opposing surfaces of said electrical interconnection means.

13. The structure of claim 12, wherein said enlarged end at one of said first and second opposing surfaces of said electrical interconnection means is sphere and spheroid.

14. The structure of claim 13, wherein said enlarged end at the other of said first and second opposing surfaces of said electrical interconnection means is hemispherical and hemispheroidal having a flattened face with a projection on said flattened face.

15. The structure of claim 1, wherein said structure is a three dimensional electronic packaging structure.

16. The structure according to claim 1, wherein each of said plurality of electrical conductors has an enlarged end at least one of said first and second opposing surfaces of said electrical interconnection means, said enlarged end having a flattened surface.

17. The structure comprising:

a first and second assembly;

5,371,654

13

an electrical interconnection means;
 said first assembly is disposed adjacent said second
 assembly so that a first surface of said first assembly
 is adjacent a second surface of said second assembly;
 each of said first and second assemblies comprises:
 a substrate having first and second opposing faces;
 a substrate contains electrical conductors;
 said first surface and said second surface have a
 plurality of electrical contact locations disposed
 thereon;
 a plurality of electronic devices disposed on said
 first surface;
 said electrical interconnection means comprises:
 a layer of elastomeric material having first and
 second opposing surfaces;
 said layer has a plurality of apertures extending
 from said first surface to said second surface of
 said layer;
 a plurality of electrical contact locations on a first
 side and a second side of said layer electrically
 interconnected by a plurality of conductors ex-
 tending from said first surface to said second
 surface of said layer;
 said electrical interconnection means is disposed on
 said first side of said first substrate so that said
 electronic devices on said first surface of said first
 substrate are disposed in said apertures in said elec-
 trical interconnection means;
 said electrical contact locations on said second side of
 said layer of said electrical interconnection means
 are electrically interconnected with electrical
 contact locations on said first side of said substrate
 of said first assembly;
 said electrical contact locations on said first side of
 said layer of said electrical interconnection means
 are electrically interconnected with electrical

14

contact locations on said second side of said sub-
 strate of said second assembly.

18. The structure of claim 17, wherein said substrate
 is formed from a material selected from the group con-
 sisting of diamond and diamond-like materials.

19. The structure of claim 18, further including a
 means for pressing said first and said second assembly
 together to press said electrical interconnection means
 therebetween.

20. The structure of claim 19, further including a heat
 dissipation means in thermal contact with said structure.

21. The structure of claim 20, wherein said heat dissi-
 pation means is in thermal contact with said substrate of
 said first and said second assembly.

22. A structure comprising:

a substrate having a plurality of contact locations
 thereon;

an electrical interconnection means;

said electrical interconnection means comprises a
 dielectric material having first and second oppos-
 ing surfaces and a plurality of electrical conductors
 extending from said first to said second opposing
 surfaces of said electrical interconnection means;
 each of said plurality of electrical conductors has a
 first end at said first surface;

each of said first ends of said plurality of conductors
 has a protuberance with a flattened surface;
 said flattened surface is in electrical contact with at
 least one of said plurality of contact locations.

23. The structure according to claim 22, wherein said
 flattened surface has a projection thereon.

24. The structure according to claim 22, wherein said
 dielectric material is an elastomeric material.

25. The structure according to claim 22, wherein said
 second end has a protuberance thereat.

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